



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

17/B  
P. Ullrich  
8-8-03

Re Patent Application of:

Yoshihiro MORI et al.

Serial No. 09/942,038

Filed: August 30, 2001

For: A METHOD FOR FABRICATING  
SEMICONDUCTOR DEVICE INCLUDING  
ANNEALING AN ELECTRODE IN A  
REDUCING ATMOSPHERE BEFORE  
CAPACITOR INSULATING FILM FORMING  
(AS AMENDED)

)  
) Group Art Unit: 2813  
) Examiner: Yen-nhu B. Huynh  
) Confirmation No.  
) Date: July 18, 2003

CERTIFICATE OF MAILING OR TRANSMISSION  
[37 CFR 1.8(a)]

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Signature: \_\_\_\_\_

Name: Jeannie Saxton

AMENDMENT

Mail Stop \_\_\_\_\_  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Examiner's Office Action mailed February 28, 2003, the due date for which having been extended two months (2) to July 28, 2003, please consider the following amendments and remarks in connection with the above-identified application.

RECEIVED  
JUL 29 2003  
TECHNOLOGY CENTER 2800

IN THE TITLE:

Please change the title of the present application to read as follows:

“A METHOD FOR FABRICATING SEMICONDUCTOR DEVICE INCLUDING ANNEALING AN  
ELECTRODE IN A REDUCING ATMOSPHERE BEFORE CAPACITOR INSULATING FILM FORMING”.